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(54)Title: GENUINE/COUNTERFEIT DISCRIMINATING METHOD, GENUINE/COUNTERFEIT DISCRIMINATION OBJECT, AND GENUINE/COUNTERFEIT DISCRIMINATING DEVICE

(54)発明の名称 真偽判別方法、真偽判別対象物および真偽判別装置

(57) Abstract

A genuine/counterfeit discriminating method characterized in that combinations of an electric field pattern, a magnetic pattern, an electron beam reaction pattern, and reflection or absorption patterns of visible light, ultraviolet radiation, and infrared radiation are discriminated by means of an electric field, magnetism, an electron beam, visible light, ultraviolet radiation, or infrared radiation. A genuine/counterfeit discrimination object characterized in that combinations of an electric field pattern, a magnetic pattern, an electron beam reaction pattern, and reflection or absorption patterns of visible light, ultraviolet radiation, and infrared radiation are recognized by means of an electric field, magnetism, an electron beam, visible light, ultraviolet radiation, or infrared radiation. A genuine/counterfeit discriminating device characterized by comprising any combination of a device for discriminating electric field patterns, a device for discriminating magnetic patterns, a device for discriminating electron beam reaction patterns, a device for discriminating visible light patterns, a device for discriminating ultraviolet radiation patterns, and a device for discriminating infrared radiation patterns, and a device for comparing patterns obtained by the devices from one another and discriminating them.

